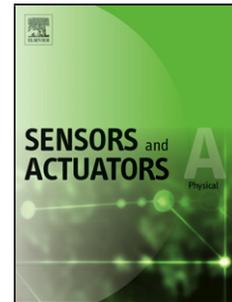


## Accepted Manuscript

Title: A low voltage silicon micro-pump based on piezoelectric thin films

Author: Pierre-Henri Cazorla Olivier Fuchs Martine Cochet  
Sandrine Maubert Gwenael Le Rhun Yves Fouillet  
id="aut0035" biographyid="vt0030"  
orcid="0000-0003-1462-8969"> Emmanuel Defay



PII: S0924-4247(16)30433-2  
DOI: <http://dx.doi.org/doi:10.1016/j.sna.2016.09.012>  
Reference: SNA 9826

To appear in: *Sensors and Actuators A*

Received date: 20-1-2016  
Revised date: 7-9-2016  
Accepted date: 8-9-2016

Please cite this article as: Pierre-Henri Cazorla, Olivier Fuchs, Martine Cochet, Sandrine Maubert, Gwenael Le Rhun, Yves Fouillet, Emmanuel Defay, A low voltage silicon micro-pump based on piezoelectric thin films, *Sensors and Actuators: A Physical* <http://dx.doi.org/10.1016/j.sna.2016.09.012>

This is a PDF file of an unedited manuscript that has been accepted for publication. As a service to our customers we are providing this early version of the manuscript. The manuscript will undergo copyediting, typesetting, and review of the resulting proof before it is published in its final form. Please note that during the production process errors may be discovered which could affect the content, and all legal disclaimers that apply to the journal pertain.

## A low voltage silicon micro-pump based on piezoelectric thin films

*Pierre-Henri Cazorla<sup>1</sup>, Olivier Fuchs<sup>1</sup>, Martine Cochet<sup>1</sup>, Sandrine Maubert<sup>1</sup>, Gwenael Le Rhun<sup>1</sup>, Yves Fouillet<sup>1</sup>, Emmanuel Defay<sup>1,2</sup>*

<sup>1</sup> CEA, LETI, MINATEC Campus, F-38054 Grenoble, France and Univ. Grenoble Alpes, F-38000 Grenoble, France

<sup>2</sup> Luxembourg Institute of Science and Technology LIST, Materials Research and Technology Department, L-4422 Belvaux, Luxembourg

Download English Version:

<https://daneshyari.com/en/article/5008573>

Download Persian Version:

<https://daneshyari.com/article/5008573>

[Daneshyari.com](https://daneshyari.com)